

Docket No. 241315US2CONT/shb



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Eiji SHIDOJI, et al.

SERIAL NO: 10/635,816

GAU:

FILED: August 7, 2003

EXAMINER:

FOR: SPUTTERING APPARATUS AND SPUTTER FILM DEPOSITION METHOD

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references, some of which are cited in the attached International Search Report listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- ☐ A check is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment form is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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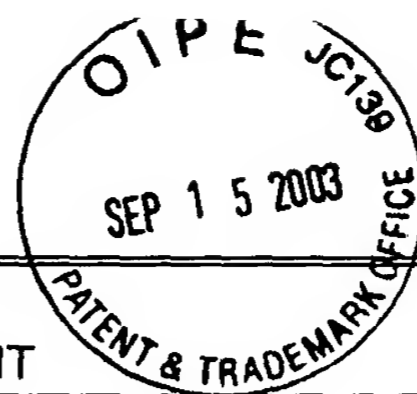
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STATEMENT OF RELEVANCY

Reference AU (JP 49-115085) on Form 1449:

A method for forming a thin film, comprising forming a thin film by sputtering, ion plating, electron beam vapor deposition, ion beam deposition, resistance heating and the like, characterized in that the method comprises intermittently making energy supply, and measuring a property of the thin film thus formed in an off-time period of the energy supply.

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
241315US2CONTSERIAL NO.
10/635,816

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT
Eiji SHIDOJI, et al.FILING DATE
August 7, 2003

GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AH	1 046 727	10/25/2000	EUROPE (with corr. JP 2001-3166)		
	AI	2001-3166	01/09/2001	JAPAN		X
	AJ	7-109569	04/25/95	JAPAN		X
	AK	8-325725	12/10/96	JAPAN		X
	AL	4-173971	06/22/92	JAPAN		X
	AM	6-207269	07/26/94	JAPAN		X
	AN	5-21347	01/29/93	JAPAN		X
	AO	3-253568	11/12/91	JAPAN (with English Abstract)		X
	AP	11-241162	09/07/99	JAPAN (with English Abstract)		X
	AQ	6-212421	08/02/94	JAPAN (with English Abstract)		X
	AR	5-222531	08/31/93	JAPAN (with English Abstract)		X
	AS	5-222530	08/31/93	JAPAN (with English Abstract)		X
	AT	10-330934	12/15/98	JAPAN (with English Abstract)		X
	AU	49-115085	11/02/74	JAPAN		X
	AV					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AW	
	AX	
	AY	
	AZ	<input type="checkbox"/> Additional References sheet(s) attached

Examiner

Date Considered

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.